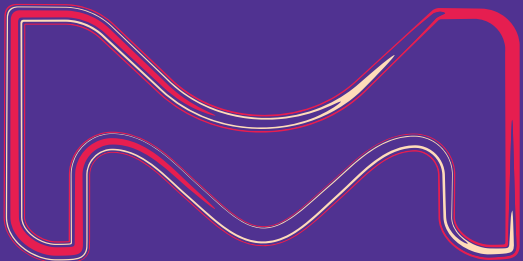


AZ[®] 10XT (520 CP) photoresist performance

Comparison to AZ[®] 9260



MERCK

Overview

AZ[®] 10XT (520 cP) photoresist was tested side by side vs. AZ[®] 9260 at a film thickness of 12.0 μm.

The two products were compared for coat uniformity, thermal stability, and lithographic performance on silicon as follows.

AZ® 10XT (520 cP) vs. AZ® 9260 Photoresist

Process Conditions:

Optitrac Coat/ Bake

Coat: Static dispense

Substrate: 150mm HMDS primed silicon

Target Film Thickness: 12.0 μm

Spin Speed: 1370 rpm for 30 sec

Softbake: 110°C hotplate/ 180 sec contact

Exposure: Ultratech 1500 gh line stepper, increment 125 mJ/cm²

Develop: AZ® 400K 1:4, 260 sec continuous spray @ 27°C

Analysis:

Hitachi S4700 SEM

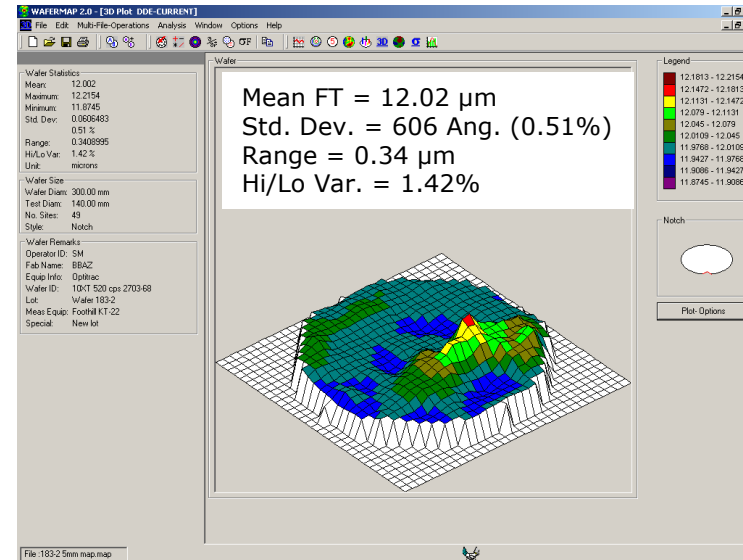
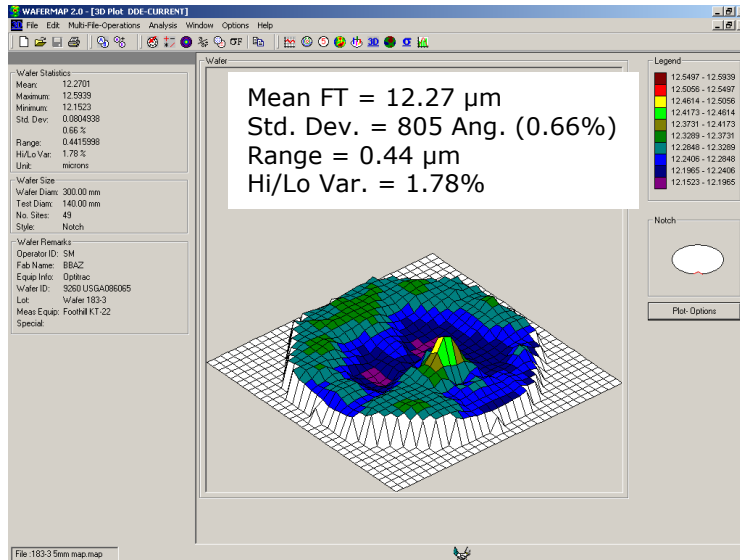
AZ[®] 10XT (520 cP) vs. AZ[®] 9260 Photoresist

Target 12.0 μm FT on 150 mm Silicon by Hand Dispense

5 mm Edge Exclusion Map

AZ[®] 9260
Spin 30 sec @ 1370 rpm

AZ[®] 10XT
Spin 30 sec @ 1370 rpm



No difference in coat uniformity between the two products

AZ[®] 10XT (520 cP) vs. AZ[®] 9260 Photoresist

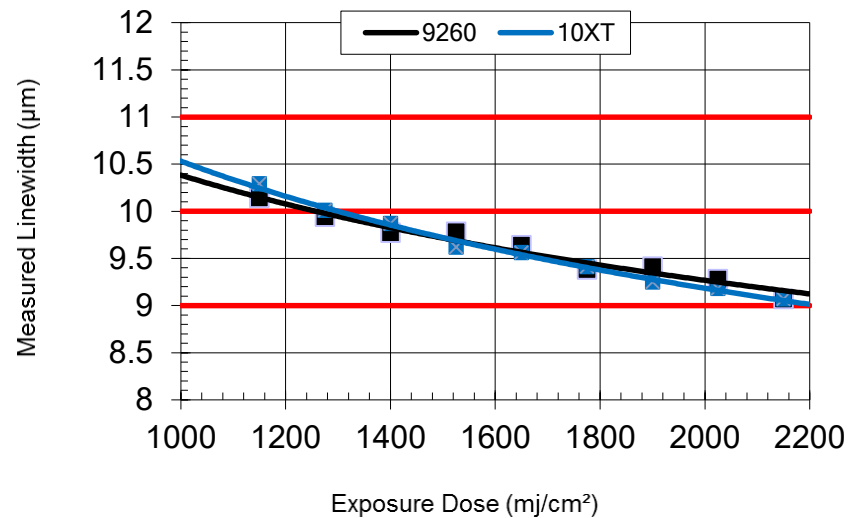
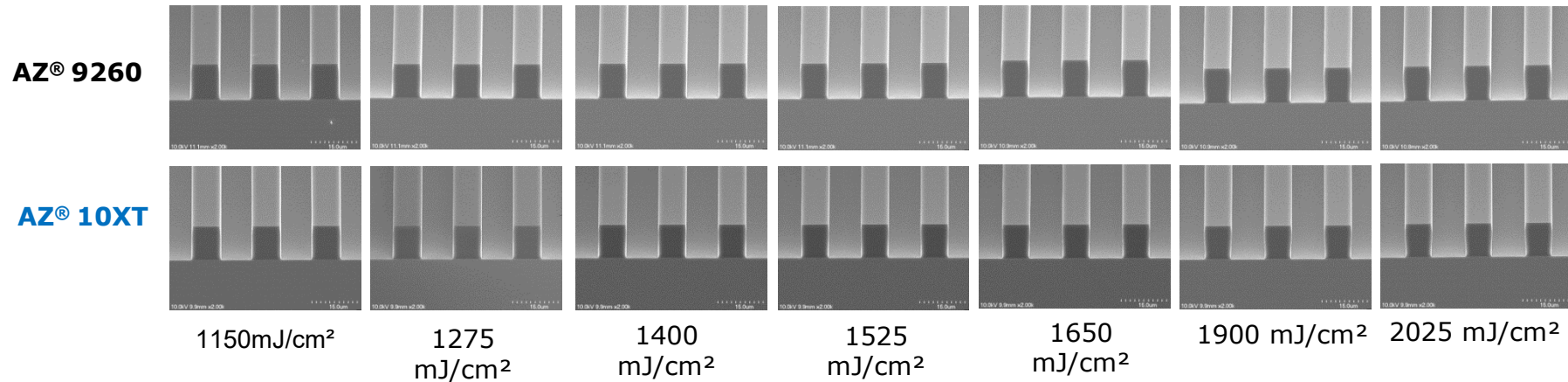
Performance Summary on Silicon at 12.0 μm Film Thickness

Product	Features (1:1)	Film Thickness (μm)	DTP 10.0 μm (mJ/cm^2)	Exposure Latitude 10.0 μm (%)	DOF 10.0 μm (μm)	Linearity (μm)
AZ [®] 9260	Dense Lines	12.0	1257	134	18.0	1.8
AZ [®] 10XT	Dense Lines	12.0	1283	108	18.0	1.8

Comparable lithographic performance between the two products

AZ[®] 10XT (520 cP) vs. AZ[®] 9260 Photoresist

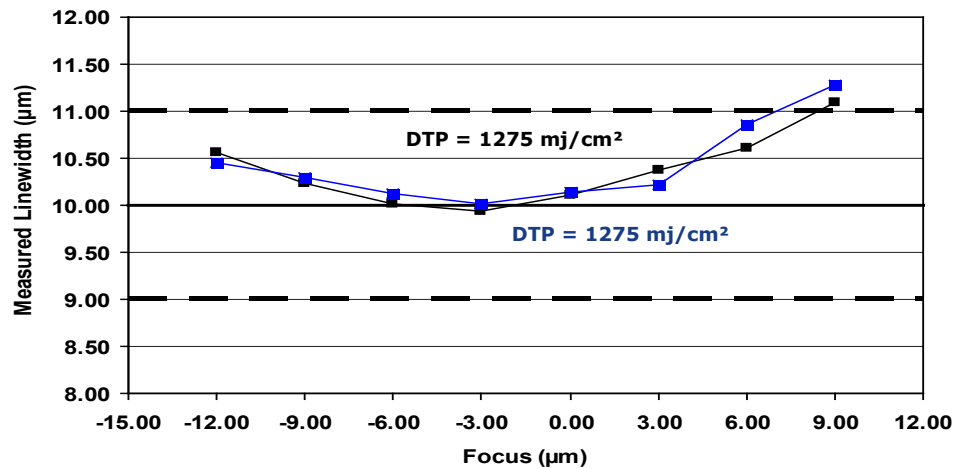
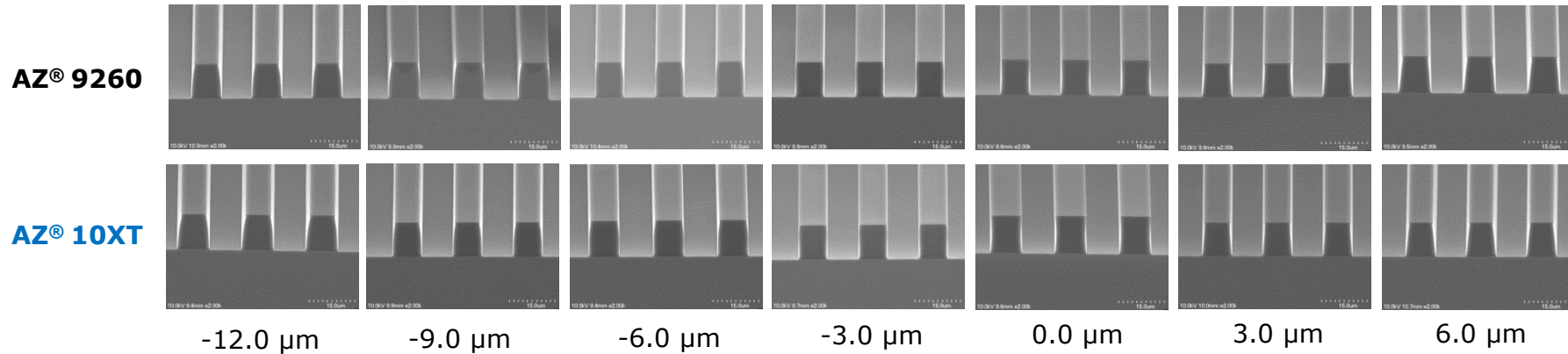
Exposure Latitude on Silicon; FT=12.0 μm; 10.0 μm L/S



Film Thickness: 12.0 μm
 Optitrac coater
 SB: 110°C/ 180 sec contact
 Ultratech 1500 g-h Line Stepper
 AZ[®]400K 1:4, 260 sec continuous spray @ 27 °C

AZ[®] 10XT (520 cP) vs. AZ[®] 9260 Photoresist

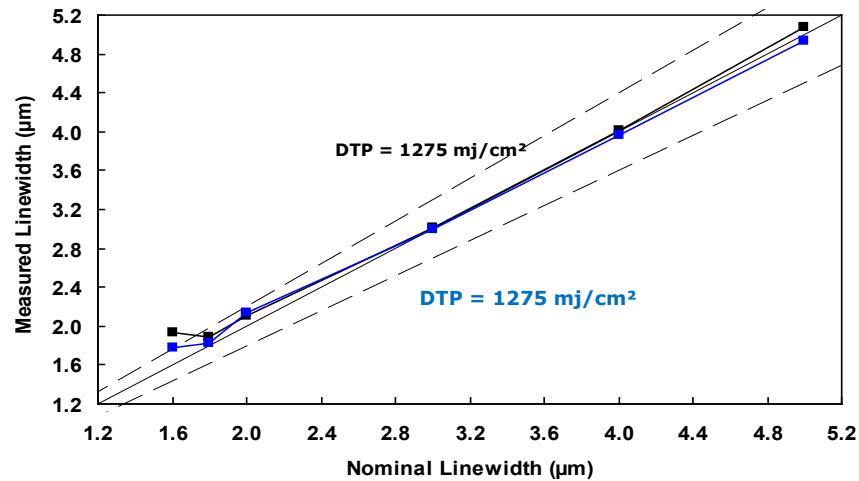
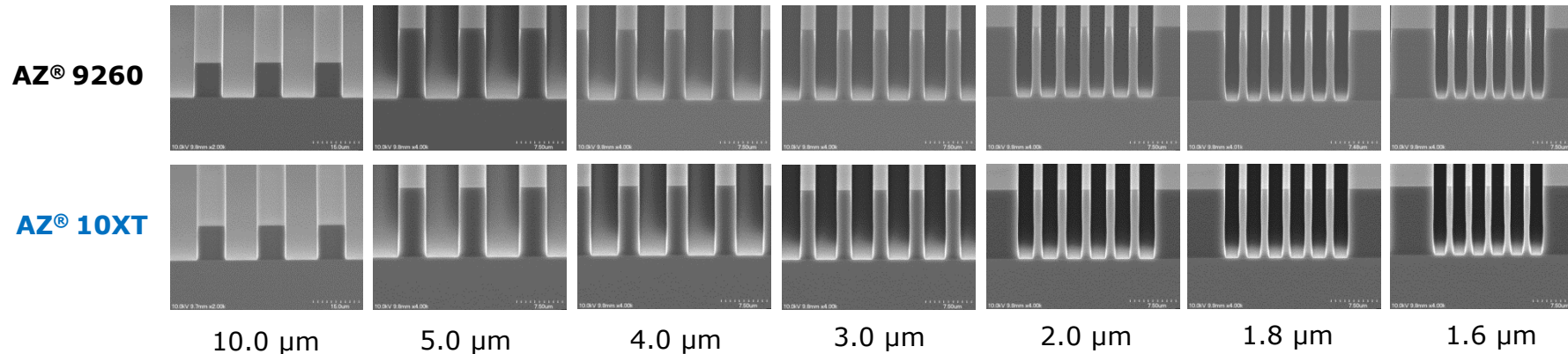
Depth of Focus on Silicon; FT=12.0 μm; 10.0 μm L/S



Film Thickness: 12.0 μm
 Optitrac coater
 SB: 110°C/ 180 sec contact
 Ultratech 1500 g-h Line Stepper
 AZ[®]400K 1:4, 260 sec continuous spray @ 27 °C

AZ[®] 10XT (520 cP) vs. AZ[®] 9260 Photoresist

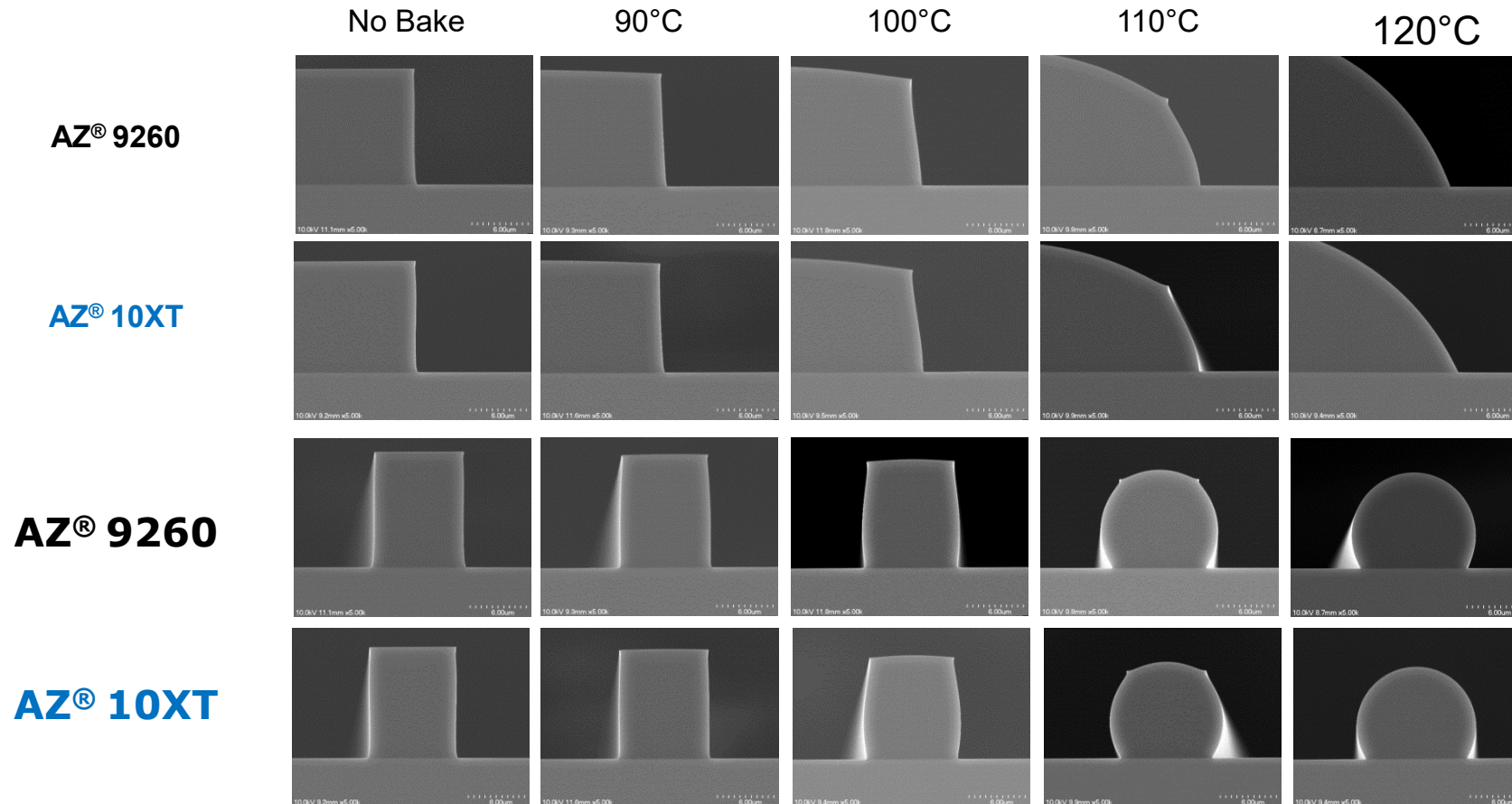
Linearity on Silicon; FT=12.0 μm; F= -3.0 μm; L/S



Film Thickness: 12.0 μm
 Optitrac coater
 SB: 110°C/ 180 sec contact
 Ultratech 1500 g-h Line Stepper
 AZ[®]400K 1:4, 260 sec continuous spray @ 27 °C

AZ[®] 10XT (520 cP) vs. AZ[®] 9260 Photoresist

Thermal Stability on Si for Large Pads and 10.0 μm Lines



Film Thickness: 12.0 μm
Optitrac coater
SB: 110°C/ 180 sec contact
Ultratech 1500 g-h Line Stepper
AZ[®]400K 1:4, 260 sec continuous spray @ 27 °C

Summary

AZ[®] 10XT showed no difference in coat uniformity or thermal stability compared to AZ[®] 9260.

Lithographic performance for these two products was virtually identical.

